

**Electromechanical transducer has piezoelectric elements in stack with intermediate contact electrodes in form of flat connecting vanes fed out of flexible circuit board**

**Publication number:** DE10028319

**Publication date:** 2001-12-13

**Inventor:** BIRGEL DIETMAR (DE)

**Applicant:** ENDRESS HAUSER GMBH CO (DE)

**Classification:**

**- international:** H01L41/047; H04R17/00; H04R31/00; H05K1/18; H01L41/00; H04R17/00; H04R31/00; H05K1/18; (IPC1-7): H04R17/00; G01F23/28; H05K1/18

**- European:** H01L41/047; H04R17/00B

**Application number:** DE20001028319 20000607

**Priority number(s):** DE20001028319 20000607

**Also published as:**

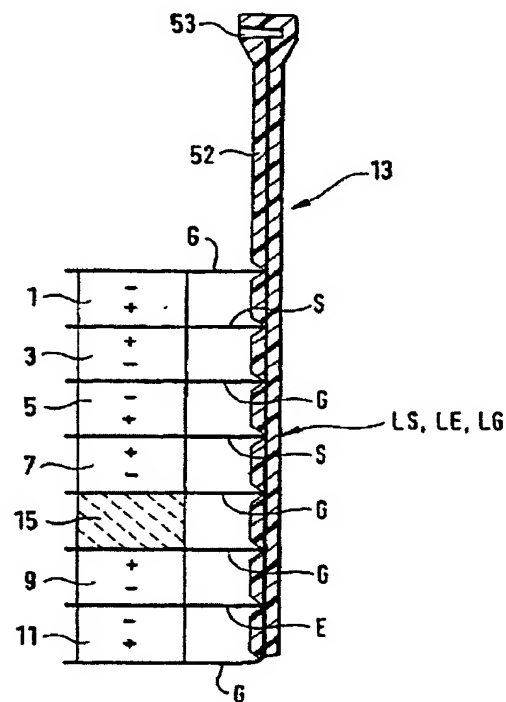
WO0195667 (A1)  
US6946779 (B2)  
US2003168945 (A1)  
EP1287720 (A0)  
CN1433662 (A)

more >>

**Report a data error here**

**Abstract of DE10028319**

The device has piezoelectric elements (1,3,5,7,9,11) in a stack with contact electrodes (G,S,E) between the piezoelectric elements and via which electrical connections are made to the piezoelectric elements, whereby the contact electrodes are in the form of flat connecting vanes fed out of a flexible circuit board (13). The circuit board has a stepped region with a vane fed out of each step. An independent claim is also included for a method of manufacturing an electromechanical transducer and a device for determining and/or monitoring a defined level in a container.



Data supplied from the [esp@cenet](mailto:esp@cenet) database - Worldwide